Low Energy Ion Scattering Quantitative Surface Analysis

$$
E_{S} = k \cdot E_{P} = \left(\frac{\cos\Theta + \sqrt{\left(\frac{M_{S}}{M_{P}}\right)^{2} - \sin^{2}\Theta}}{1 + \frac{M_{S}}{M_{P}}}\right)^{2} \cdot E_{P}
$$

for $\frac{M_{S}}{M_{P}} \ge 1$

Energy of scattered ions (ES) is following the laws of the conservation of energy and momentum

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Features of Low Energy Ion Scattering (LEIS)

- Ultra-high surface sensitivity, top atomic layer analysis
- ˃ Static depth profiling information (up to 10 nm)
- ˃ Reliable and straight-forward quantification
- ˃ Simple analysis of insulators and rough samples
- > Detection of all elements > He
- Detection limits (of 1 ML):
	- $Li O \ge 1\%$
	- $F Cl$ 1 % 0.05 %
	- K U 500 ppm 10 ppm

Brongersma et al., Surf. Sci. Rep. 62 (2007) 63

Brongersma, Low-Energy Ion Scattering, in: Characterization of Materials, Wiley (2012)

Extreme Surface Sensitivity using Noble Gas Ions

> Neutralization effect of noble gas ions when penetrating the surface allows for extreme surface sensitivity

Double Toroidal Energy Analyzer

IONTOF 5

Sample

- > Crucial for practical work: Analysis before destruction
- > High sensitivity and high-resolution analyzer:
	- \checkmark Parallel detection of energy
	- \checkmark Parallel acceptance of angles (azimuth)
	- \checkmark Well defined scattering angle for high mass resolution

> Switching to Ne and Ar scattering

expands mass scale for heavier elements

Spectroscopy and Static Depth Profiling

- > Ions can be scattered at the surface, giving element specific surface peak
- ˃ Ions are also scattered in deeper layers, undergoing an additional energy loss proportional to the depth
- ˃ When scattered in the volume, a re-ionization at the surface is required for detection. This is promoted by some elements (e. g. oxygen) and gives tails to the left of the peaks
- > Energy loss can be converted to depth

$ZrO₂$ Atomic Layer Deposition on Silicon

İONTOF

ZrO₂ Atomic Layer Deposition on Silicon

- > Correlation plots: Extrapolation to both axes gives sensitivity factors for pure materials
- > This allows reference free quantification in two component systems (and in many cases also with three components)

$ZrO₂$ on Si: A non-ideal ALD process

- ˃ Zr peaks develops a tail long before reaching maximum intensity (= layer closure)
- > Coverage and thickness can be measured independently

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Catalysis

(Almost) No Influence of Surface Roughness

- > Analysis of catalysts with huge surface area routinely done
- > Depth of field of analyzer: approx. 500 µm

Table 2. Relative LEIS yields of a flat quartz sample and pressed silica powders (300 MPa) with specific surface areas of 50-380 m^2 g⁻¹

Jansen et al., Surf. Interface Anal. **36** (2004) 1469

FoV: 300 x 300 µm²

> Pressure gap

- Pressure inside the reactor: ≈ 10 bar
- Pressure inside the analysis chamber: $\approx 10^{-6} 10^{-10}$ mbar
- > Structure gap
	- Low loading, rough surfaces (1000 m^2/g) inside the reactor
	- High loading and flat surfaces inside the analysis chamber
- > The Qtac bridges the structure gap but the pressure gap exists partially.
- > Workaround
	- In-situ preparation of the catalyst with subsequent quenching

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Single atom heterogeneous catalysis

- improved efficiency, higher reactivity, and better selectivity
- lower loading of precious metals

- > Pt/CeO₂, prepared using atom trapping
- $> 1, 2, 3, 4$ wt. % Pt, 10 h @ 800° C in air
- At higher loading, large Pt particles expected
- Small Pt particles are not stable at elevated T, evaporation of PtO₂
	- \rightarrow either single atoms or large particles

Jones et al., Science (2016)

ACS Catalysis, 2019, DOI: 10.1021/acscatal.8b04885

SAC - 3 keV He⁺ scattering

- Samples and Pt metal cleaned using atomic oxygen \rightarrow no C, organics
- > No unexpected elements at the surface
- $>$ Mass resolution not sufficient for Ce/Pt \rightarrow Ne scattering

ACS Catalysis, 2019, DOI: 10.1021/acscatal.8b04885

- > Excellent mass resolution
- ˃ Quantification by comparison to Pt reference

- Determine LEIS signal for reference PtO₂ 6820 cts/nC
- > Calculate PtO₂ density of reference: 9.01 PtO₂/nm²
- > Calculate PtO₂ density of samples: Y_{LEIS}/6820 * 9.01 PtO₂/nm²

Apply small roughness correction – catalyst and reference are very different

IONTOF

ACS Catalysis, 2019, DOI: 10.1021/acscatal.8b04885

- $>$ At 1 and 2 wt. %, Pt is present as single atom catalyst quantitative agreement, no normalization
- > At 3 % loading, 77 % of the atoms are detected in the outer layer
- At 4 % loading, 69 % of the atoms are in the outer layer
- > As large particles only minimally contribute to the surface, their signal is weak in LEIS

Coated particles

Pt + Al_2O_3 nanoparticles

- ˃ Nanoscale Pt particles are desirable for catalytic activity **and** efficiency
- ˃ Problem: Particle coarsening due to harsh thermal and chemical conditions during catalysis
- $>$ Idea: ALD Al₂O₃ overcoating to prevent particle coarsening

Solano, Dendooven et al. Nanoscale, 2020, 12, 11684–11693, DOI: 10.1039/d0nr02444a

Coated particles

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- ˃ XRF (RBS calibrated) quantifies total Pt amount
- ˃ in-situ GISAXS measures particles coarsening
- $>$ LEIS quantifies availability of Pt even after Al₂O₃ overcoat
- ˃ Key result: Isolated particles are required to prevent coarsening by ALD

Solano, Dendooven et al. Nanoscale, 2020, 12, 11684–11693, DOI: 10.1039/d0nr02444a

Ultra-thin films

- > Mo surface peak:
	- − Symmetric Gaussian: (sub-)monolayer coverage
	- Peak integral proportional to fraction of surface covered
	- − Tail for >1 monolayer developing Samples courtesy of

Jeong-Gyu Song

Diffusion study with in-situ heating – Mo/Si layers

 $>$ 5 nm Si / 1.6 nm B₄C / 10 nm Mo, annealing @ 660 deg. C

V. de Rooij-Lohmann, *Appl. Phys. Lett.* **94** 063107 (2009) V. de Rooij-Lohmann, *J. Appl. Phys.* **108** 014314 (2010)

- > 5 nm Si / 1.6 nm B₄C / 10 nm Mo, annealing @ 500 deg. C
- > Diffusion coefficient without B₄C : $(8 \pm 2) \cdot 10^{-20}$ m²/s
- > Diffusion coefficient with 1.6 nm B₄C: $(4 \pm 1) \cdot 10^{-21}$ m²/s

V. de Rooij-Lohmann, *J. Appl. Phys.* **108** 014314 (2010)

- ˃ Sputter and analysis beam conditions are optimised independently
- ˃ Sputtering using inert species (usually Ar) at low energy to assure high depth resolution
- ˃ Scattering using a noble gas ion beam selected for optimum sensitivity and mass resolution for the elements of interest

Sputter area: 2 x 2 mm² Analysis area: 1.5 x 1.5 mm²

- > 500 eV Ar sputter profile before and after heating to 300 °C
- > Mn is enriched at the surface and below the Ru
- > Enrichment increased by heating \rightarrow diffusion through Ru film

Energy materials

Electrode/electrolyte interface stabilization

- > Li transparent passivation coating on electrode surfaces
- $>$ Wet chemical Al₂O₃ on LiCoO₂ nano-platelets
- > Calcination at 400°C, 500°C, 600°C for 3 h (Al-400, Al-500, Al-600)
- > EDX mapping shows coating, diffusion of Al present into core
- > Quantification of surface coverage impossible
- > XRD also sees diffusion with T

Electrode/electrolyte interface stabilization

Hu et al., *Chem. Mater.* 2017, 29, 5896−5905, DOI: 10.1021/acs.chemmater.7b01269

750

1000

1250

1500

Energy (eV)

1750

2000

2250

 $0.0 + 500$

- > LEIS detects Al and residual Co at the surface (incomplete coating/diffusion)
- > Sub-surface Co hardly changing
- > Several 10 % Na detected (wet chemistry)

Electrode/electrolyte interface stabilization

Hu et al., *Chem. Mater.* 2017, 29, 5896−5905, DOI: 10.1021/acs.chemmater.7b01269

- > Calcination stimulates diffusion processes
- > No complete intermixing (otherwise Co surface coverage would be much higher in LEIS) \rightarrow Al ox preferred at surface, also seen in LEIS on CoAl₂O₄

> At similar coulombic efficiency, normalised discharge capacity best for Al-600

- > $(La, Sr)₂NiO₄$ is a candidate for SOFC cathodes ionic O conductor
- ˃ Authors use LEIS, CTR and angle resolved XPS to analyzer low index faces of as-is and heat treated crystals (450°C, 72 h in air)
- > LEIS data shows surface termination

La₂NiO₄ single crystals

M. Burriel et al., *Energy Environ. Sci.* **7**, 311 (2014)

IONTOE

˃ Angle resolved XPS and CTR less surface sensitive

Absence of Ni on outer layer of Sr doped

˃ Agreement with LEIS findings: no Ni in (110) and (001) w/ and w/o annealing

5.9 3.4 ± 0.4 4.6 ± 0.6 6.6 3.1 ± 0.4 4.7 ± 0.5 4.5 ± 0.4 7.0 2.3 ± 0.2 **Bulk (theoretical)** 2.0 2.0

Fig. 2 Crystal truncation rod scattering as measured along the OOL direction in air at 450 °C. Red dots indicate the raw data and solid lines the model CTR patterns for NiO₂ (blue) or (La, Sr)O (green) terminations.

La₂NiO₄ single crystals

- Fuel cell performance limited by oxygen exchange between solid electrolyte and gas phase
- ˃ Kinetics determined by transport properties and surface chemistry
- > Interface usually not accessible to surface analysis \rightarrow model structure

traditional porous electrode micropatterned LSCF electrodes on YSZ electrolyte

J. Druce et al., *Nucl. Instr. Meth. B*, **332** (2014) 261-265

Laterally resolved analysis of fuel cell electrodes

- ˃ Laterally resolved analysis is possible (here: 5 keV Ne scattering)
- > Image resolution \approx 5 µm

J. Druce et al., *Nucl. Instr. Meth. B*, **332** (2014) 261-265

˃ LSCF step and electrolyte show no Au signal

- > LSCF mainly terminated by Sr
- > Electrolyte shows some La: Diffusion? Patterning? Electrochemical testing?
- > Electrolyte shows no Y or Zr \rightarrow monolayer contamination by

 \leftrightarrow

82.5 um

165 um

330 um

x/4 $x/2$

LSCF

YSZ

X

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Summary

- ˃ Low energy ion scattering (LEIS) is the most surface sensitive technique available - top atomic layer characterisation
- > Static depth profiling provides detailed information up to 10 nm
- ˃ LEIS provides straight-forward and matrix effect free quantification
- > The superior sensitivity of the Qtac100 double toroidal energy analyser allows real static LEIS analysis even with heavier projectiles at higher energies.
- ˃ The time-of-flight mass filtering significantly improves detection limits
- > Ideal in combination with other analytical techniques such as TOF-SIMS or XPS

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Example 2 detail

otac¹⁰⁰